

'What is claimed is:

1. A plasma-enhanced processing apparatus, comprising;

    a process chamber in which a substrate is processed,

    a pumping system that pumps said process chamber,

    a gas-introduction system that introduces process gas into

    said process chamber,

    a plasma-generation means that generates plasma in said

    process chamber by applying energy to said process gas,

    a substrate holder that holds said substrate in said

    process chamber,

    wherein an opposite electrode facing to said substrate held

    by said substrate holder is provided, and the opposite electrode

    comprises a clamping mechanism that clamps the front board to

    support said front board.

2. A plasma-enhanced processing apparatus as claimed in claim 1,

    wherein;

        said opposite electrode comprises a main body, and a

        cooling mechanism that cools said front board via said main body.

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3. A plasma-enhanced processing apparatus as claimed in claim 1

or 2, wherein;

        said clamping mechanism clamps the periphery of said front

board by a clamping plate in surface contact with said front board.

4. A plasma-enhanced processing apparatus as claimed in claim 3, wherein;

said front board has a step at said periphery that is sandwiched by said main board and said clamping plate, and said clamping plate is flush with said front board.

5. A plasma-enhanced processing apparatus as claimed in claim 1, comprising;

a protector covering a surface of said clamping mechanism, wherein said surface is not exposed to said plasma.

6. A plasma-enhanced processing apparatus as claimed in claim 1, wherein;

said clamping mechanism clamps the periphery of said front board by a clamping plate in surface contact on said front board, and said protector is flush with said front board.

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7. A plasma-enhanced processing apparatus as claimed in claim 1, ~~2, 3, 4, 5 or 6~~, wherein;

said front board is made of silicon poly-crystal or silicon mono-crystal.

8. A plasma-enhanced processing apparatus as claimed in claim 3,

wherein;

said clamping plate is screwed on a member except said front board to press said front board onto said main body, and screwing torque is 1Nm or more.

9. A plasma-enhanced processing apparatus as claimed in claim 6,

wherein;

said clamping plate is screwed on a member except said front board to press said front board onto said main body, and screwing torque is 1Nm or more.

10. A plasma-enhanced processing apparatus as claimed in claim 1, wherein;

a sheet made of carbon is inserted between said main body and said front board.